Cheng-Yao Lo

List of Publications by Year in descending order

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| 50 papers | 566 citations | 567281 15 h-index | 677142 22 g-index |
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| 51 all docs | 51 docs citations | 51 times ranked | 412 citing authors |

| # | Article | IF | CITATIONS |
|----|--|------|-----------|
| 1 | Smart manufacturing powered by recent technological advancements: A review. Journal of Manufacturing Systems, 2022, 64, 236-250. | 13.9 | 44 |
| 2 | MEMS-Controlled Paper-Like Transmissive Flexible Display. Journal of Microelectromechanical Systems, 2010, 19, 410-418. | 2.5 | 39 |
| 3 | Highly transparent and excellent electromagnetic interference shielding hybrid films composed of sliver-grid/(silver nanowires and reduced graphene oxide). Materials Letters, 2019, 253, 152-155. | 2.6 | 38 |
| 4 | Novel roll-to-roll lift-off patterned active-matrix display on flexible polymer substrate. Microelectronic Engineering, 2009, 86, 979-983. | 2.4 | 36 |
| 5 | Mutual Capacitive Flexible Tactile Sensor for 3-D Image Control. Journal of Microelectromechanical Systems, 2013, 22, 804-814. | 2.5 | 34 |
| 6 | Capacitive tactile sensor with asymmetric electrodes for angle-detection-error alleviation. Sensors and Actuators A: Physical, 2016, 250, 159-169. | 4.1 | 27 |
| 7 | Vertically stacked capacitive tactile sensor with more than quadrupled spatial resolution enhancement from planar arrangement. Sensors and Actuators A: Physical, 2017, 263, 386-390. | 4.1 | 26 |
| 8 | Friction-Assisted Pulling Force Detection Mechanism for Tactile Sensors. Journal of Microelectromechanical Systems, 2014, 23, 471-481. | 2.5 | 23 |
| 9 | Porosity reduction in inkjet-printed copper film by progressive sintering on nanoparticles. Thin Solid Films, 2017, 627, 33-38. | 1.8 | 23 |
| 10 | Realization of Multistage Detection Sensitivity and Dynamic Range in Capacitive Tactile Sensors. IEEE Sensors Journal, 2020, 20, 9724-9732. | 4.7 | 20 |
| 11 | Investigation of transparent and conductive undoped Zn2In2O5â^'x films deposited on n-type GaN layers. Journal of Applied Physics, 2002, 92, 274-280. | 2.5 | 19 |
| 12 | Capacitive tactile sensor for angle detection and its accuracy study. IEEE Sensors Journal, 2016, , 1-1. | 4.7 | 19 |
| 13 | Doubling the spatial resolution in capacitive tactile sensors. Journal of Micro/ Nanolithography, MEMS, and MOEMS, 2017, 16, 035001. | 0.9 | 18 |
| 14 | Five-fold sensitivity enhancement in a capacitive tactile sensor by reducing material and structural rigidity. Sensors and Actuators A: Physical, 2019, 293, 167-177. | 4.1 | 18 |
| 15 | Mechanical stress-controlled tunable active frequency-selective surface. Applied Physics Letters, 2017, 110, . | 3.3 | 15 |
| 16 | Soft and flexible sensor array using carbon black pillars for object recognition via pressure mapping. Measurement: Journal of the International Measurement Confederation, 2020, 159, 107781. | 5.0 | 15 |
| 17 | Post-lithography pattern modification and its application to a tunable wire grid polarizer. Nanotechnology, 2013, 24, 115306. | 2.6 | 12 |
| 18 | A High Sensitivity Three-Dimensional-Shape Sensing Patch Prepared by Lithography and Inkjet Printing. Sensors, 2012, 12, 4172-4186. | 3.8 | 11 |

| # | Article | IF | Citations |
|----|---|-----|-----------|
| 19 | Highly elastic and flexible multi-layered carbon black/elastomer composite based capacitive sensor arrays for soft robotics. Measurement: Sensors, 2019, 2-4, 100004. | 1.7 | 11 |
| 20 | Development and Characterization of Vertically Stacked Tactile Sensor With Hollow Structure. IEEE Sensors Journal, 2021, 21, 5809-5818. | 4.7 | 10 |
| 21 | Critical dimension and pattern size enhancement using pre-strained lithography. Applied Physics Letters, 2014, 105, 154103. | 3.3 | 9 |
| 22 | CMOS-MEMS thermal-piezoresistive oscillators with high transduction efficiency for mass sensing applications. , 2017, , . | | 9 |
| 23 | Zero power consumption visual curvature sensor by flexible interferometer. Sensors and Actuators A: Physical, 2011, 169, 295-300. | 4.1 | 8 |
| 24 | Thermoresistive Strain Sensor and Positioning Method for Roll-to-Roll Processes. Sensors, 2014, 14, 8082-8095. | 3.8 | 8 |
| 25 | Methodology for evaluating pattern transfer completeness in inkjet printing with irregular edges. Journal of Micromechanics and Microengineering, 2016, 26, 065009. | 2.6 | 7 |
| 26 | Continuous inkjet-patterned and flashlight-sintered strain sensor for in-line off-axis detection in Roll-to-Roll manufacturing. Mechatronics, 2019, 59, 95-103. | 3.3 | 7 |
| 27 | Novel Response Acquisition Method for Enhancing Spatial Resolution in Capacitive Tactile Sensing Array. IEEE Sensors Journal, 2021, 21, 5895-5903. | 4.7 | 7 |
| 28 | Enlarging a post-lithography pattern modification process window with a Poisson's ratio-matching inter-layer. Microelectronic Engineering, 2014, 127, 97-101. | 2.4 | 6 |
| 29 | Morphology and conductivity improvement of metal mesh through rollâ€toâ€rollâ€compatible nearâ€infrared sintering. Micro and Nano Letters, 2017, 12, 886-890. | 1.3 | 6 |
| 30 | Efficient and improved qualification method for patterns with irregular edges in printed electronics. Journal of Micromechanics and Microengineering, 2019, 29, 124005. | 2.6 | 5 |
| 31 | Advanced qualification method for patterns with irregular edges in printed electronics. Flexible and Printed Electronics, 2019, 4, 015001. | 2.7 | 5 |
| 32 | Structure compensation and illumination uniformity improvement through inkjet printing in organic light-emitting diode subpixels. Journal of Vacuum Science and Technology B:Nanotechnology and Microelectronics, 2017, 35, 020601. | 1.2 | 3 |
| 33 | Inkjet-patterned porous split-ring resonator and its performance study on metamaterial application. Journal of Micromechanics and Microengineering, 2018, 28, 095012. | 2.6 | 3 |
| 34 | Surface plasmon resonance manipulation through application of mechanically generated planar and linear strain. Applied Physics Express, 2019, 12, 096504. | 2.4 | 3 |
| 35 | Advancements in Polymeric Capacitive Tactile Sensors. , 2019, , . | | 3 |
| 36 | Enhancing the Detection Sensitivity in Capacitive Tactile Sensors With Optimized Electrode Shapes. IEEE Sensors Journal, 2021, 21, 26294-26303. | 4.7 | 3 |

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| 37 | Machine learning-based off-line electrical characteristic prediction through in-line pattern integrity inspection. Journal of Micromechanics and Microengineering, 2021, 31, 015005. | 2.6 | 3 |
| 38 | Numerical analysis of a microelectromechanical system-based color filtering device with surface plasmon resonance modulation. Displays, 2018, 54, 20-27. | 3.7 | 2 |
| 39 | An integrated method based on energy concentration for evaluating normally distributed spectra in the visible region. Displays, 2019, 57, 7-17. | 3.7 | 2 |
| 40 | Calibrations on Shear Angle Detections in Vertically Stacked Capacitive Tactile Sensors. IEEE Sensors Journal, 2021, 21, 26269-26276. | 4.7 | 2 |
| 41 | Electromagnetic characteristic estimation on spiral antennas through AOI, ML, and AI. Flexible and Printed Electronics, 2022, 7, 025012. | 2.7 | 2 |
| 42 | Morphology and conductivity enhancement of metal mesh in OLEDs by near infrared and intense pulse light. , $2017, , .$ | | 1 |
| 43 | Surface plasmonic resonance modulation by MEMS-elastomer hybrid system. , 2018, , . | | 1 |
| 44 | Strain sensor with low thermal conductivity concealing resin for enhanced detection sensitivity and improved spatial resolution. Journal of Micromechanics and Microengineering, 2019, 29, 124001. | 2.6 | 1 |
| 45 | Linear strain maximization in MEMS-elastomer hybrid configurations for isotropic electromagnetic modulations in stretchable electronics. Displays, 2020, 64, 101963. | 3.7 | 1 |
| 46 | 51.3: Pulling Force Sensing Unit for 3D Image Movement. Digest of Technical Papers SID International Symposium, 2013, 44, 713-716. | 0.3 | 0 |
| 47 | Nano metal crack initiation on polymer and its optical application with tunable metal dimensions. , 2014, , . | | O |
| 48 | Extensive Sensitivity Enhancement in Stacked Capacitive Tactile Sensors., 2019,,. | | 0 |
| 49 | Advanced Capacitor Arrangement for Enhanced Spatial Resolution in Tactile Sensors. , 2020, , . | | 0 |
| 50 | Multifunction Force Sensor with Hollow Structure., 2020,,. | | 0 |